

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. 29318US2	SERIAL NO. <i>10/809,092</i>
<b>INFORMATION DISCLOSURE CITATION BY APPLICANT</b> <i>(USE SEVERAL SHEETS IF NECESSARY)</i>				APPLICANT: Min-Su Fung, et al.	
				FILING DATE:	GROUP ART UNIT: <i>2529</i>

  

U.S. PATENT DOCUMENTS							
Examiner Initial	Document No.	Date	Name	Class	Subclass	Filing Date If Appropriate	
<i>VN</i>	A	4,236,165	Szedon				
<i>VN</i>	B	4,812,756	Curtis, et al.				
<i>VN</i>	C	5,216,362	Verkuil				
<i>VN</i>	D	5,498,974	Verkuil, et al.				
<i>VN</i>	E	5,767,693	Verkuil				
<i>VN</i>	F	5,834,941	Verkuil, et al.				
	G						
	H						

  

FOREIGN PATENT DOCUMENTS							
Document No.	Date	Country	Class	Subclass	Translation		
I							
J							

  

OTHER REFERENCES <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>	
<i>VN</i>	K Solid State Technology, Test/Masurement, "Monitoring Electrically Active Contaminants to Assess Oxide Quality", Gregory S. Horner, et al., June 1985, PennWell Publishing Company, 4 Pages.
<i>VN</i>	L Semiconductor International, "A New Approach for Measuring Oxide Thickness", Tom G. Miller, July 1995, Cahners Publishing Company, 2 Pages.
<i>VN</i>	M "COS Testing Combines Expanded Charge Monitoring Capabilities with Reduced Costs", Michael A. Peters, Semiconductor Fabtech 95, 4 Pages.
<i>VN</i>	N Process Monitoring, "Corona Oxide Semiconductor Test", Semiconductor Test Supplement, February/March 1995, Pages S-3 and S-5.
<i>VN</i>	O "Quantox™ Non-Contact Oxide Monitoring System", John Bickley, 1995 Keithley Instruments, Inc., No. 1744, 6 Pages. <i>(month unavailable)</i>

  

Examiner: <i>mh Nguye</i>	Date Considered <i>12/09/04</i>
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**\*Examiner:** Initial if reference considered, regardless of whether citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.